

EUVL Source Workshop October 29, 2001

8:00 AM	Introduction	
	EUVLLC-SNL, ASET, SEMATECH	
8:15 AM	ASML	Jos Benschop
8:35 AM	Nikon	Katsuhiko Murakami
8:55 AM	Cymer	Igor Fomenkov
9:15 AM	TRW	Luis Espinoza
9:35 AM	JMAR	Edmond Turcu
9:55 AM	<i>Break</i>	
10:15 AM	Gigaphoton	Hakaru Mizoguchi
10:35 AM	Xtreme	Uwe Stamm
10:55 AM	Philips	Joseph Pankert
11:15 AM	SNL	Glen Kubiak
11:35 AM	Plex	Malcolm McGeoch
11:45 AM	Innolite	Bert Junno
11:55 AM	<i>Lunch</i>	
1:00 PM	Breakout	Break into 2 groups
2:00 PM	Read out from breakout	All
2:30 PM	Close mtg	

Minutes of the Source Workshop



EVL Source Workshop
October 29, 2001
Kunibiki Messe
Matsue City, Japan





Meeting Objective:

- **Update the requirements for EUVL sources**
- **Review the developments on EUVL sources**
- **Identify critical issues for source development**
- **Thermal engineering & management challenges**

Breakout:

- 1) each group brainstorm the challenges (critical issues) for achieving high power EUV sources**

- 2) each group prioritize what are the most important issues that need to be addressed first for achieving high power EUV sources**

Next Source Meeting?

- 1) 1-2 days Thurs & Fri before SPIE
Feb 28 & March 1, 2002, California
- 2) 1 day Friday of SPIE
March 8, 2002 California
- 3) 1-2 days
March or April 2002 Austin, Tx